Wojciech Majstrzyk

List of Publications by Year
in descending order

24	150	1307594 7	1199594 12
papers	citations	h-index	g-index

25	25	25	162
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Hierarchical approach for the rational construction of helix-containing nanofibrils using Î±,Î²-peptides. Nanoscale, 2021, 13, 4000-4015.	5.6	8
2	MEMS displacement generator for atomic force microscopy metrology. Measurement Science and Technology, 2021, 32, 065903.	2.6	2
3	Adhesion as a component of retention force of overdenture prostheses-study on selected Au based dental materials used for telescopic crowns using atomic force microscopy and contact angle techniques. Journal of the Mechanical Behavior of Biomedical Materials, 2021, 121, 104648.	3.1	7
4	Soft piezoresistive cantilevers for adhesion force measurements. Sensors and Actuators A: Physical, 2020, 301, 111747.	4.1	5
5	Near-zero contact force atomic force microscopy investigations using active electromagnetic cantilevers. Nanotechnology, 2020, 31, 425706.	2.6	6
6	Analysis of the electrolytically polished skeletal dentures surfaces using various nano- and microscopic technologies. Acta of Bioengineering and Biomechanics, 2019, 21, 123-129.	0.4	0
7	Thermomechanically and electromagnetically actuated piezoresistive cantilevers for fast-scanning probe microscopy investigations. Sensors and Actuators A: Physical, 2018, 276, 237-245.	4.1	11
8	Force Spectroscopy with Quantitative On-Cantilever Force Control. Proceedings (mdpi), 2018, 2, 915.	0.2	2
9	Mechanical Impedance Analysis of a Novel MEMS Photon Force Sensor. Proceedings (mdpi), 2018, 2, 921.	0.2	1
10	New design of the cantilevers for radiation pressure investigations. Microelectronic Engineering, 2018, 201, 10-15.	2.4	7
11	Electromagnetic cantilever reference for the calibration of optical nanodisplacement systems. Sensors and Actuators A: Physical, 2018, 282, 149-156.	4.1	9
12	Optimal Design of Electromagnetically Actuated MEMS Cantilevers. Sensors, 2018, 18, 2533.	3.8	15
13	Real-time stochastic response analysis as a tool for monitoring cantilever mechanical properties. Mechatronics, 2017, 44, 121-128.	3.3	0
14	Magnetoelectric versus thermal actuation characteristics of shear force AFM probes with piezoresistive detection. Measurement Science and Technology, 2017, 28, 034011.	2.6	9
15	Micromachined active test structure for scanning thermal microscopy probes characterization. Microelectronic Engineering, 2017, 174, 70-73.	2.4	6
16	Pattern-generation and pattern-transfer for single-digit nano devices. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2016, 34, .	1.2	34
17	New approach for a multi-cantilever arrays sensor system with advanced MOEMS readout. , 2016, , .		1
18	Innovative multi-cantilever array sensor system with MOEMS read-out. Proceedings of SPIE, 2016, , .	0.8	1

#	Article	IF	Citations
19	Technology of thermally driven and magnetomotively detected MEMS microbridges. Sensors and Actuators A: Physical, 2016, 240, 17-22.	4.1	7
20	Metrology of electromagnetic static actuation of MEMS microbridge using atomic force microscopy. Micron, 2016, 84, 1-6.	2.2	2
21	Closed-loop surface stress compensation with an electromagnetically actuated microcantilever. Sensors and Actuators B: Chemical, 2015, 213, 566-573.	7.8	8
22	Design, technology, and application of integrated piezoresistive scanning thermal microscopy (SThM) microcantilever. Proceedings of SPIE, 2014, , .	0.8	7
23	Quality factor and resonant frequency measurement by ARMA process identification of randomly excited MEMS/NEMS cantilever. , 2014, , .		0
24	Electromagnetically Actuated Microcantilever for Chemical and Biochemical Sensing in Static Mode. Procedia Engineering, 2014, 87, 955-958.	1.2	2